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| Form PTO-1449 (Modified) | U.S. Department of Commerce Patent and Trademark Office | Atty. Docket No. 30205/39511 | Serial No. To be Assigned |
| | | Applicant Seong Hwan Park | |
| | | Filing Date November 26, 2003 | Group 2813 To be Assigned |

INFORMATION DISCLOSURE STATEMENT

| U.S. PATENT DOCUMENTS | | | | | | | |
|-----------------------|-----------------|------------|------|-------|----------|-------------------------------|--|
| *Examiner Initials | Document Number | Issue Date | Name | Class | Subclass | Filing Date if Appropriate | |
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| FOREIGN PATENT DOCUMENTS | | | | | | | | |
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| | | | | | | Yes | No | |
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| OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.) | |
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| TN | Fujimura et al., "Ashing of the Ion Implanted Resist Layer," Digest of Papers 1989 2 nd MicroProcess Conference, July 2-5, 1989. |

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| EXAMINER | <i>[Signature]</i> | DATE CONSIDERED | 2/3/05 |
| *EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance <u>and</u> not considered. Include copy of this form with next communication to applicant. | | | |